

## Patent Abstracts of Japan

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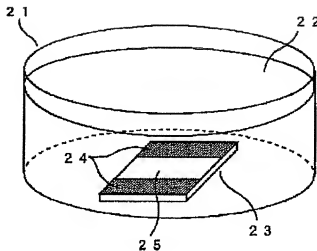
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TITLE : METHOD FOR FORMING FILM OF  
CARBON NANOTUBE, CARBON  
NANOTUBE FILM FORMED BY THE  
METHOD AND ELECTRIC FIELD  
ELECTRON RELEASE SOURCE USING  
THE SAME



ABSTRACT : PROBLEM TO BE SOLVED: To provide a method for forming a carbon nanotube film which is formed in a prescribed pattern and is useful for obtaining an inexpensive electric field electron discharge source, by using carbon nanotubes.

SOLUTION: A copper plate 23 to which adhesive tapes 24 are adhered in a prescribed pattern is put in a beaker 21 together with a solution 22 in which crude mono-layered carbon nanotubes are dispersed, and the solution 22 is then naturally evaporated to deposit the mono-layered carbon nanotubes to the copper plate 23. The adhesive tapes 24 are peeled off from the copper plate 23 to which the mono-layered carbon nanotubes are deposited, thereby giving the mono-layered carbon nanotubes tightly deposited to the copper plate 23 in the prescribed pattern. The mono-layered carbon nanotubes tightly deposited to the copper plate 23 is used as an electron-releasing source for an electron tube.

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